

THE UNIVERSITY OF CHICAGO

Serial No.: 09/914,044

Title: INSPECTION OBJECT SILICON WAFER FOR THE PURPOSE OF
DETECTING CRYSTAL DEFECTS AND THE METHOD OF
DETECTING THEREOF

Box OED

Sir:

This is to advise of a change of address for the undersigned attorneys and the forwarding of mail with regard to the matter identified in caption, as follows:

Please address all future correspondence to:

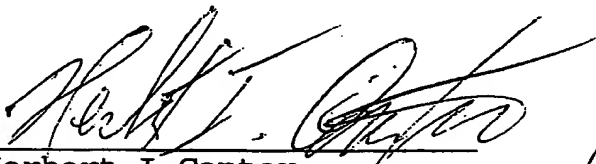
CROWELL & MORING LLP
Intellectual Property Group
P.O. Box 14300
Washington, D.C. 20044-4300


Please continue to direct all telephone and facsimile calls to:

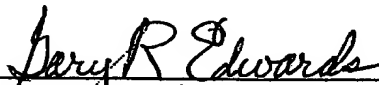
Telephone No.: (202) 628-8800
Facsimile No.: (202) 628-8844

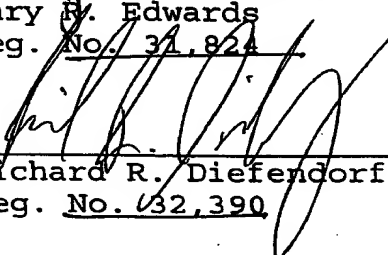
The signed original notification of this change of address, bearing the original signatures on this paper, is on


file in the U.S. Patent and Trademark Office, at the Office of Enrollment & Discipline for inspection.

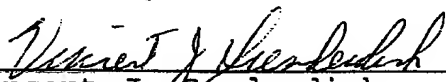

Herbert I. Cantor
Reg. No. 24,392



Donald D. Evenson
Registration No. 26,160

14- 
Gary R. Edwards
Reg. No. 31,824

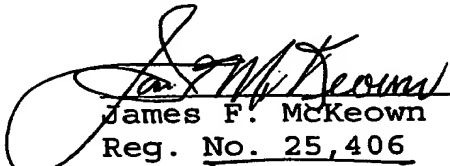

Richard R. Diefendorf
Reg. No. 32,390

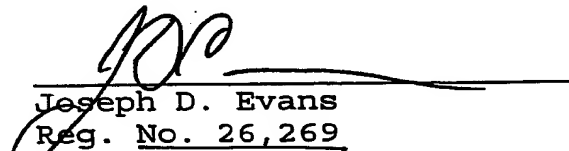

Michael I. Coe
Reg. No. 40,958



Vincent J. Sunderdick
Reg. No. 29,004

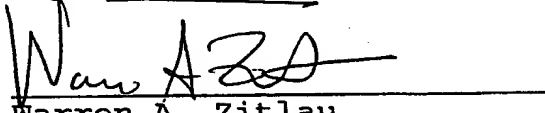

Karen Canaan
Reg. No. 42,382


Respectfully submitted,



James F. McKeown
Reg. No. 25,406

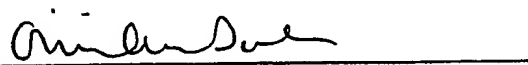

Joseph D. Evans
Reg. No. 26,269


Jeffrey D. Sanek
Reg. No. 32,169


Warren A. Zitlau
Reg. No. 39,085


Peter G. Korytnyk
Reg. No. 43,400


William G. Ackerman
Reg. No. 45,320


Olivia A. Tolan
Reg. No. 45,161

Washington, D.C.
May 1, 2001
Ref.2156/02474